# Safe Learning-based Predictive Control of Low Temperature Plasmas using Deep Neural Networks and Gaussian Processes

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## **Low Temperature Plasmas (LTPs)**

Processing of complex surfaces and interfaces

#### **Plasma Etching Process**



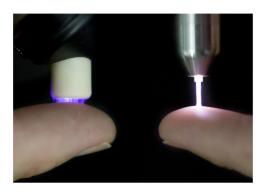
Surface Coating



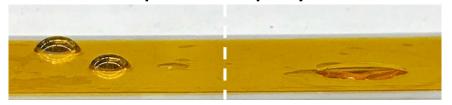
**Surface Functionalization** 



**Biomaterials Processing** 



#### Water droplets on polyimide film



Plasma treated Not treated

https://www.asbindustries.com/thermal-spray-coatings http://www.igs.titech.ac.jp/iper/english/iper2/6/detail 44.html K-D Weltmann and Th von Woedtke, 2016.

#### **Complex plasma-surface interactions:**

- Hard-to-model dynamics across multiple time- and length-scales
- Time-varying surface characteristics
- Lack of real-time diagnostics for surface properties

**Grand challenge: Reproducible and precise control** of plasma-surface interaction mechanisms

## Why Advanced Feedback Control for LTPs?

Current practice: Operating protocols for LTP sources devised offline

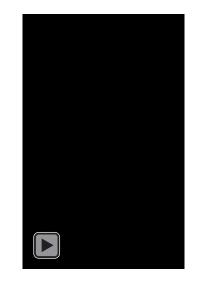
#### Why go beyond a single operating protocol?

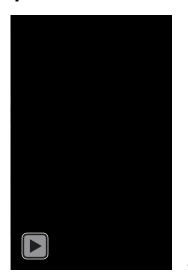
- Counter disturbances to reproducible plasma operation
  - Small changes in plasma, surface, or environment can alter fluxes to surface
  - Surface characteristics can vary from point to point and change over time
- Track plasma-induced surface effects to regulate plasma-surface interactions
  - Change plasma parameters to optimize delivery of fluxes to surface in real-time

#### Vision

- Controlled environments for studying plasma effects
- Safe and effective LTP devices for point-of-use applications
- Automated and robotic control for LTP processing of (bio)materials (e.g., using an array of LTP discharges for "large-scale" materials processing)

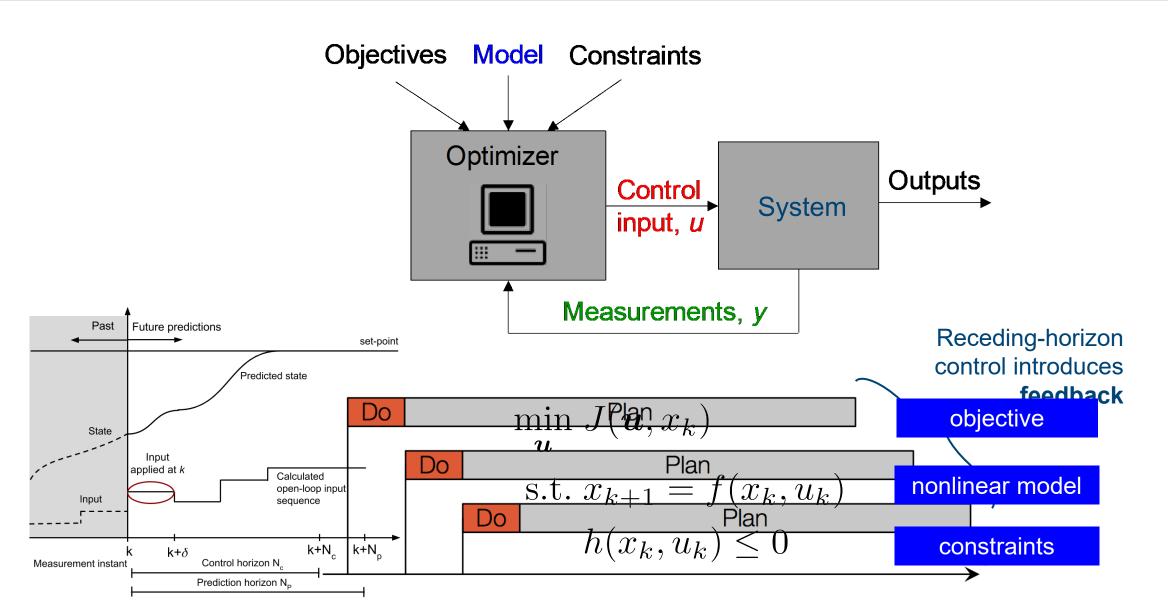
#### **Substrate Impedance Separation Distance**





## **Model Predictive Control (MPC)**

An optimization-based feedback control strategy



## **MPC Applications**

Applications over a wide range of length- and time-scales

<b>Embedded systems</b>	ns	
	μs	Energy systems
Traction control	ms	
	seconds	Smart buildings
		Smart bandings
Chemical processes	minutes	00 = 00 100 = 00 100 = 100
Obdown Stream Thompson Steam On Steam North Station Author Count Name Station	hours	Tissue engineering
Train scheduling  Train scheduling	days	
Format Mily    Control of the Contro	weeks	Production planning

## MPC for Feedback Control of LTP Processing of Complex Surfaces

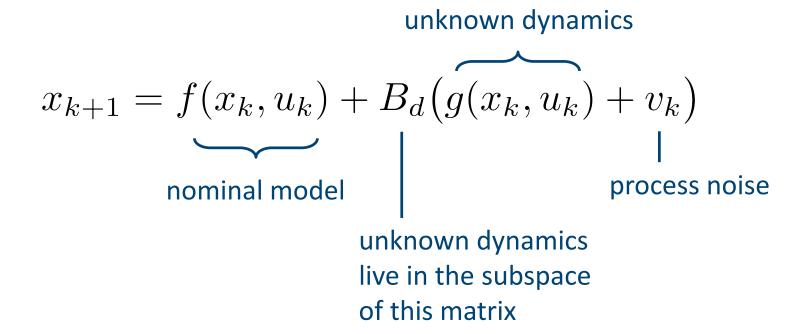
Key challenges in control of LTP applications

- Handle hard-to-model and time-varying plasma-induced surface effects:
  - Predictive models may not be available, thus there is a need for model learning "on the fly"
  - How to explore and exploit the system behavior simultaneously?
- Handle system uncertainties, imperative in safety-critical and high-performance applications:
  - Uncertainties arise from disturbances from the environment and model imperfections due to the complex nature of plasma and surface dynamics
  - How to model and incorporate uncertainty into control?
- Handle fast system dynamics and thus high measurement sampling rates:
  - There is a need for real-time diagnostics and fast control algorithms
  - How to achieve fast control computations under computational resource limitations?

Leverage stochastic optimal control theory and machine learning to address these challenges towards safe learning-based predictive control for LTPs

Mathematical representation of system dynamics

- A nominal model is augmented with a function that is learned in real-time to capture unmodeled phenomena using online data:
  - The nominal model describes our prior knowledge and can be a high-fidelity model or a data-driven model
  - Gaussian process regression is an effective approach for learning the unknown dynamics



Gaussian processes are non-parametric models and quantify uncertainty of predictions

$$y_j = B_d^{\dagger}(x_{j+1} - f(x_j, u_j)) = g(\overline{x_j}, u_j) + v_j$$



Calculate mismatch term over history *M* and store as a new dataset

$$\mathcal{D} = \{ \mathbf{y} = [y_1, \dots, y_M]^\top, \ \mathbf{z} = [z_1, \dots, z_M]^\top \}$$



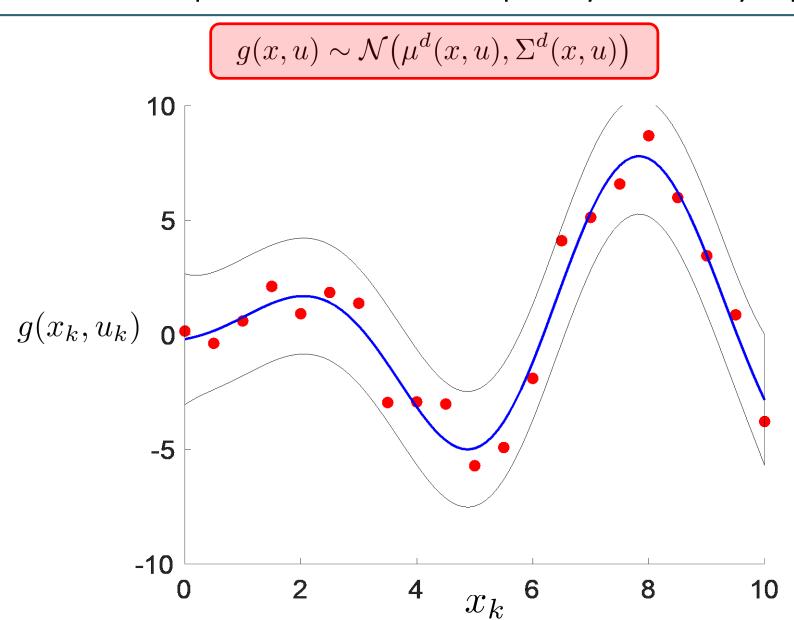
Use dataset to train a Gaussian process model that can be used to predict function at any test point

$$\mu^d(z) = m(z) + \mathbf{k}(z)^\top (\mathbf{K} + \sigma^2 I_M)^{-1} (\mathbf{y} - \mathbf{m})$$

$$\Sigma^d(z) = k(z, z) - \mathbf{k}(z)^\top (\mathbf{K} + \sigma^2 I_M)^{-1} \mathbf{k}(z)$$

Rasmussen and Williams, 2016.

Gaussian processes are non-parametric models and quantify uncertainty of predictions



Control problem that must be solved in real-time

$$\min_{\pi \in \Pi} \ \mathbb{E} \left\{ \sum_{i=0}^{N} J(x_i, u_i) \right\} \quad \frac{\text{expected performance}}{\text{(control objective)}}$$

system dynamics + uncertainty

s.t. 
$$x_{i+1} = f(x_i, u_i) + B_d(g(x_i, u_i) + v_i)$$
 decision variables  $u_i = \pi(x_i)$   $\mathcal{N}(\mu^d(x, u), \Sigma^d(x, u))$ 

$$u_i = \pi(x_i)$$

$$\mathcal{N}(\mu^d(x,u),\Sigma^d(x,u))$$

$$h(x_i, u_i) \le 0$$

 $h(x_i, u_i) \leq 0$  nonlinear state and input constraints

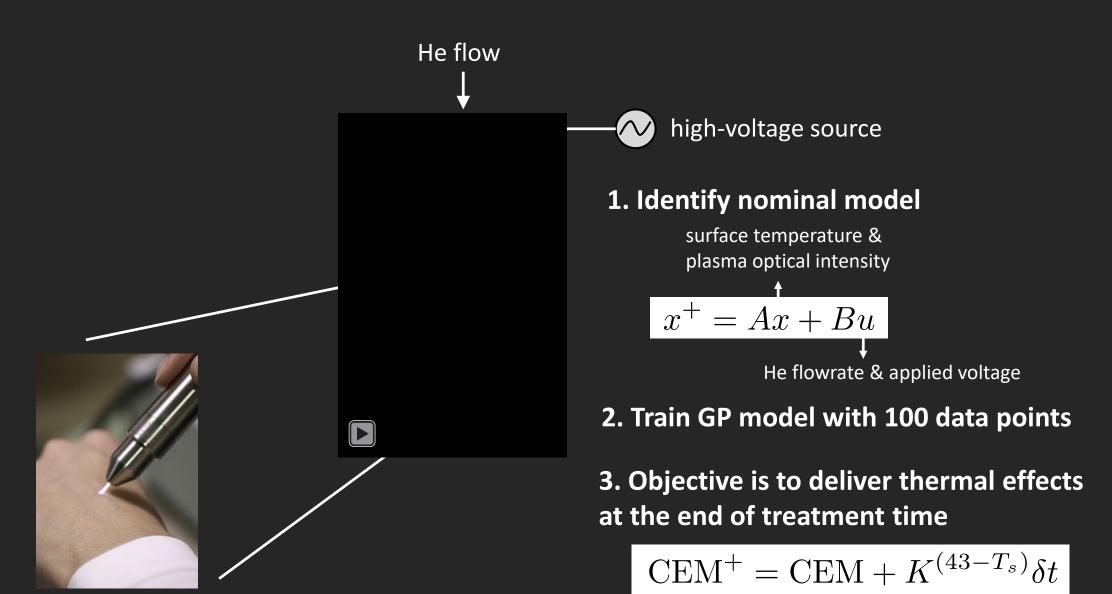
$$x_0 = x$$

 $x_0 = x$  measured state to provide feedback

$$\forall i = 0, \dots, N-1$$

Learning of unmodeled phenomena and uncertainty handling for safe learning are naturally incorporated into online decision-making

## Application to a kHz-Excited Atmospheric Pressure Plasma Jet in He



safety-critical applications in plasma medicine

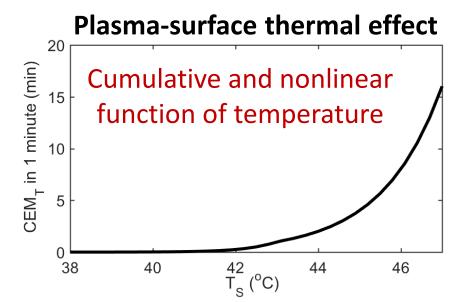
## **Delivery of Thermal Effects to Complex Surfaces**

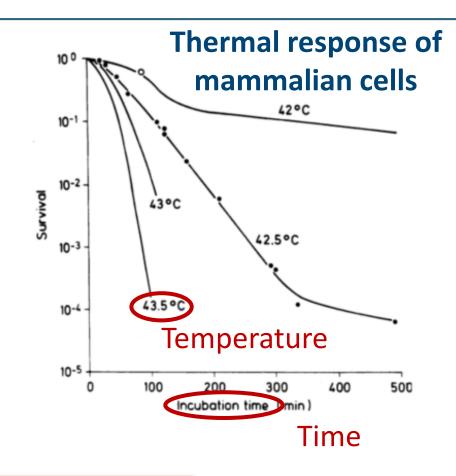
Control the cumulative thermal effects of plasma

#### **Cumulative equivalent minutes (CEM<sub>T</sub>)**

Describes cell death dependence on temperature and exposure time

$${
m CEM}_{43} = \int_0^t \! K^{(43-T_s( au))} \, d au$$
 [min]



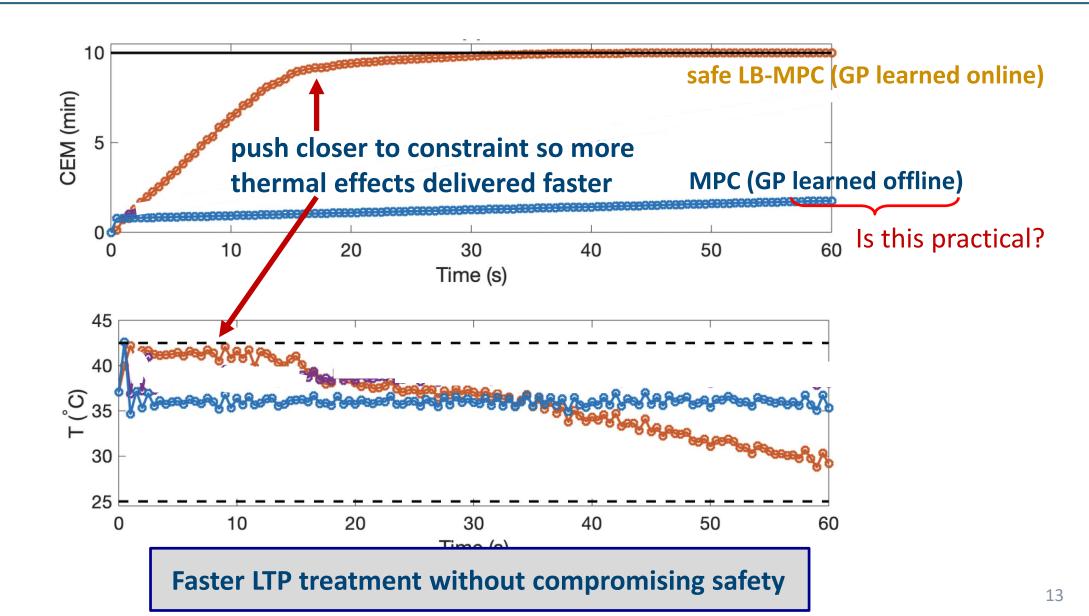


1 min at  $43^{\circ}C = 0.5$  min at  $44^{\circ}C$ 1 min at  $43^{\circ}C = 2$  min at  $42^{\circ}C$ 

Sapareto and Dewey, 1984.

#### Learning-based MPC versus MPC with an Offline Trained Model

Online learning enables significant performance improvement while honoring constraints



## **Towards Embedded Control Systems for LTPs**

Safe and effective operation of fast sampling LTP devices using inexpensive hardware

#### Real-time control hinges on fast control computations

- Online solution of the optimization problem can be expensive
- Plasmas have fast dynamics, requiring fast sampling times for feedback control
- Point-of-use and portable LTP devices require control implementations on resourcelimited embedded systems

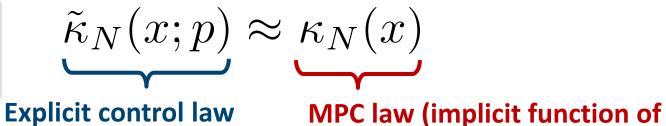
#### Fast embedded predictive control systems

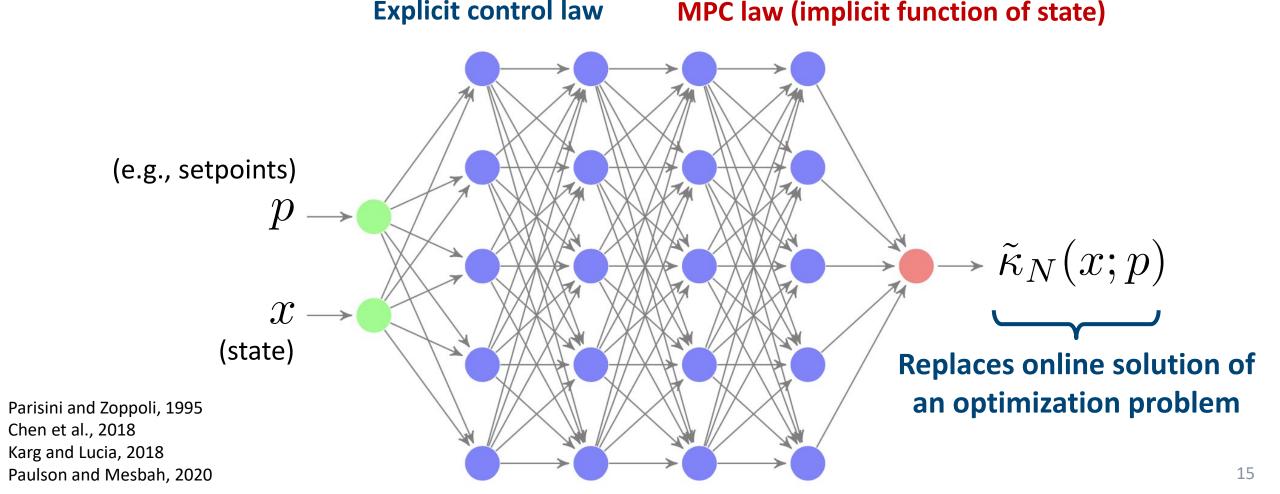
- Sub-millisecond model predictive control computations
- Control implementations on low-memory and low-power embedded systems
- Inexpensive hardware



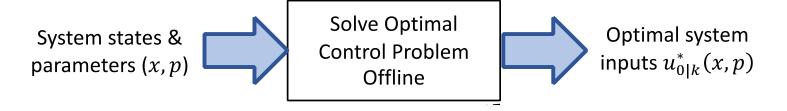
Towards embedded implementation of deep learning-based controllers

- Cheap to evaluate
- Low memory footprint

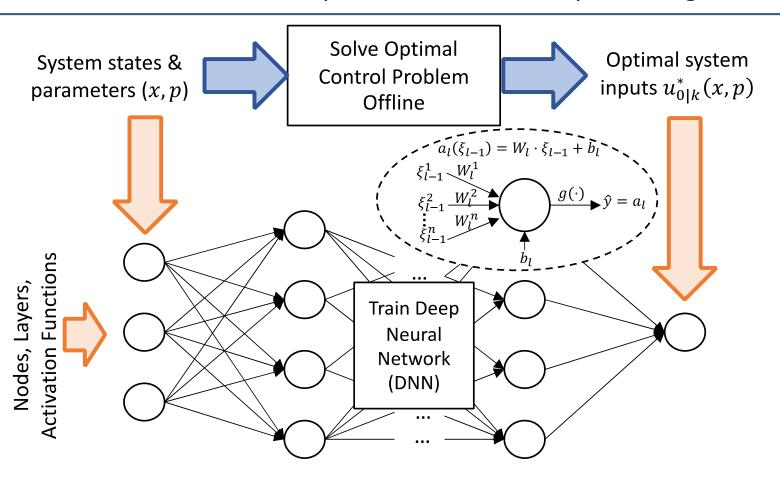




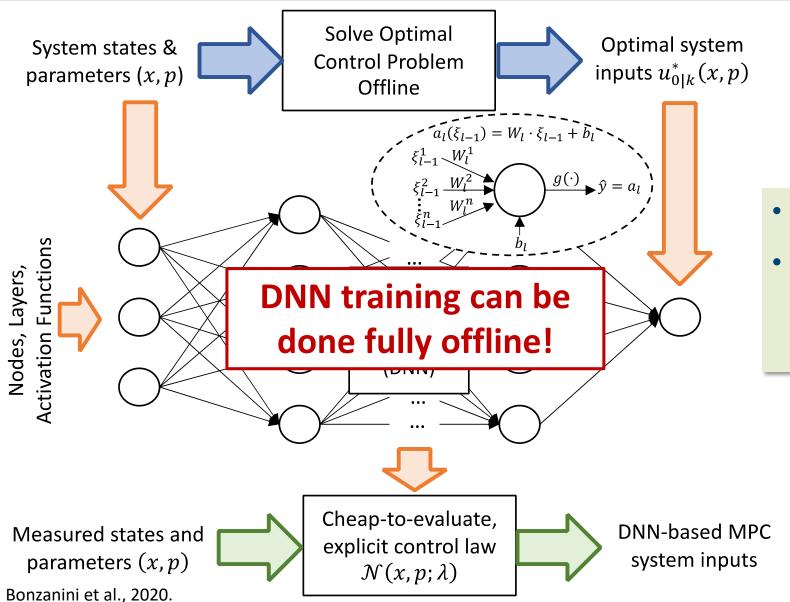
Towards embedded implementation of deep learning-based controllers



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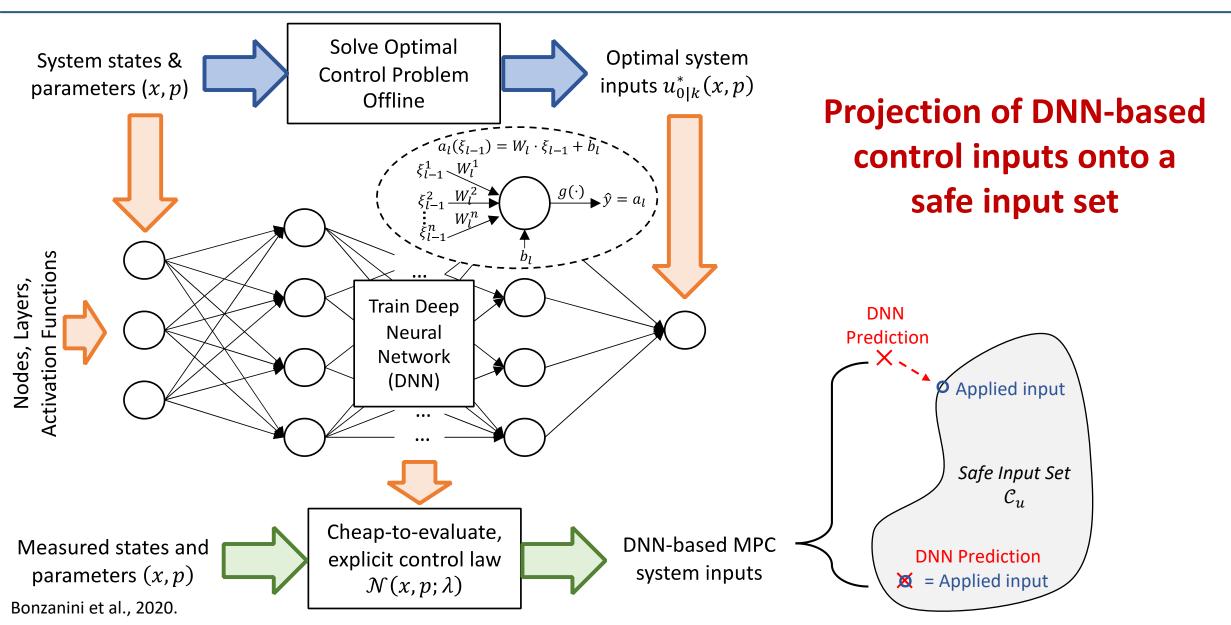
Towards embedded implementation of deep learning-based controllers



- Fast control computations
- Control inputs may no longer be robustly feasible (no guarantees on state constraint satisfaction)

**Unsafe control!** 

Towards embedded implementation of deep learning-based controllers



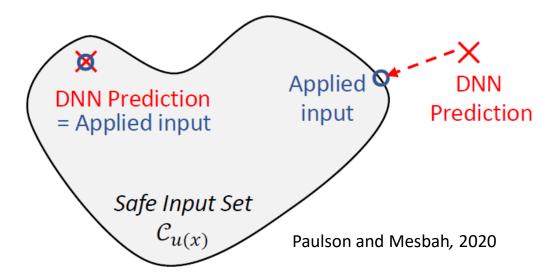
Towards embedded implementation of deep learning-based controllers

#### Safe input set

$$\mathcal{C}_u(x) = \{ u \in \mathcal{U} : f(x, u, w) \in \mathcal{C}, \ \forall w \in \mathcal{W} \}$$

#### **Robust control invariant (RCI) set**

RCI sets for linear and hybrid systems can be calculated via already-established methods

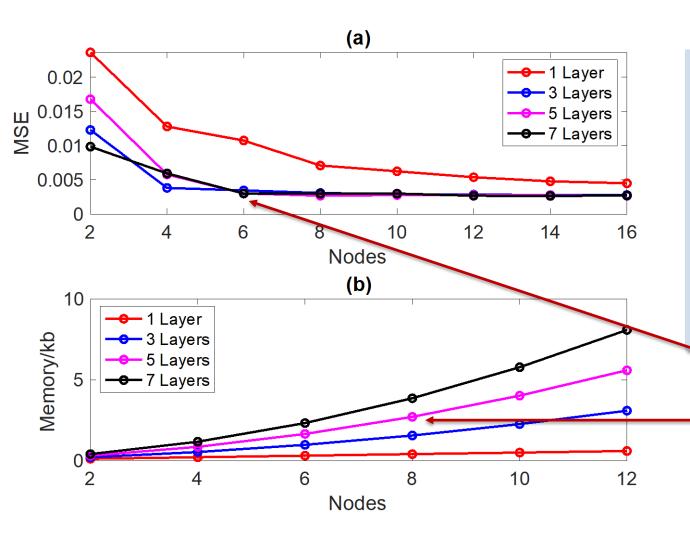


there exists for all possible feasible input disturbances 
$$\forall x \in \mathcal{C} \Rightarrow \exists u \in \mathcal{U}: f(x,u,w) \in \mathcal{C}, \ \forall w \in \mathcal{W}$$
 for all states such that successor in RCI states in RCI

$$\kappa_N^{\mathrm{proj}}(x) = \operatorname*{argmin}_{u \in \mathcal{C}_u(x)} \|u - \tilde{\kappa}_N(x)\|_2^2 \ \bigg\} \ \ \text{Safe operation guaranteed}$$

## **Training of Deep Neural Network-based MPC**

Trade-off between low error and low memory requirement

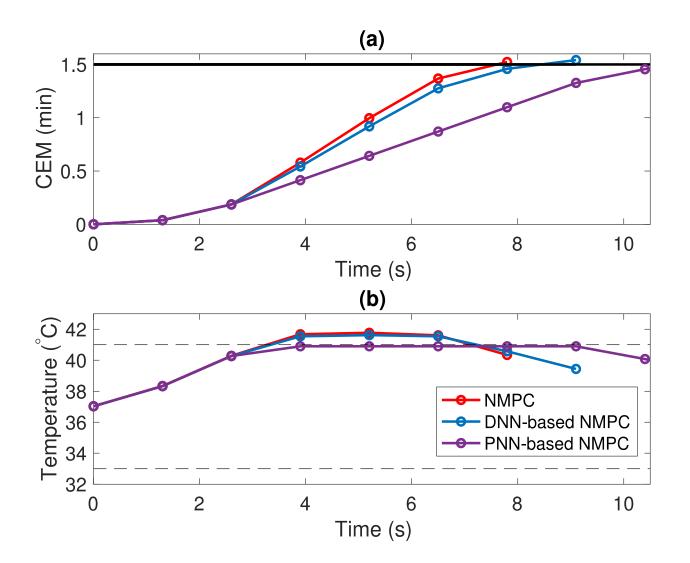


- Trained the DNN **offline** using multiple combinations of hyperparameters
- MSE decreases as number of layers and number of nodes per layer increase
- At the same time more nodes and layers correspond to a larger memory footprint
- Trade-off between accuracy and memory requirement

$$N_{
m layers} = 5$$
 $N_{
m nodes} = 6$ 

#### **Closed-loop Simulations**

DNN-based MPC provides accurate approximation



#### **NMPC and DNN-based NMPC**

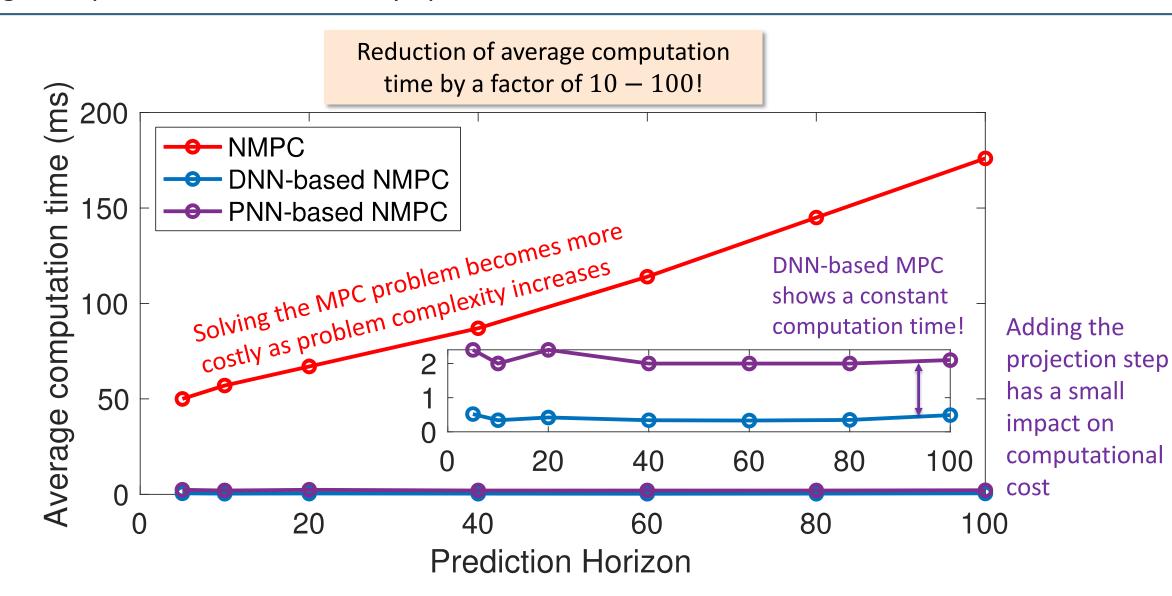
- Practically indistinguishable performance
- DNN provides an accurate approximation
- Constraint violation → may compromise safety!

#### **PNN-based NMPC**

- Worse performance (longer treatment time)
- No constraint violation
- Trade-off between robustness and performance

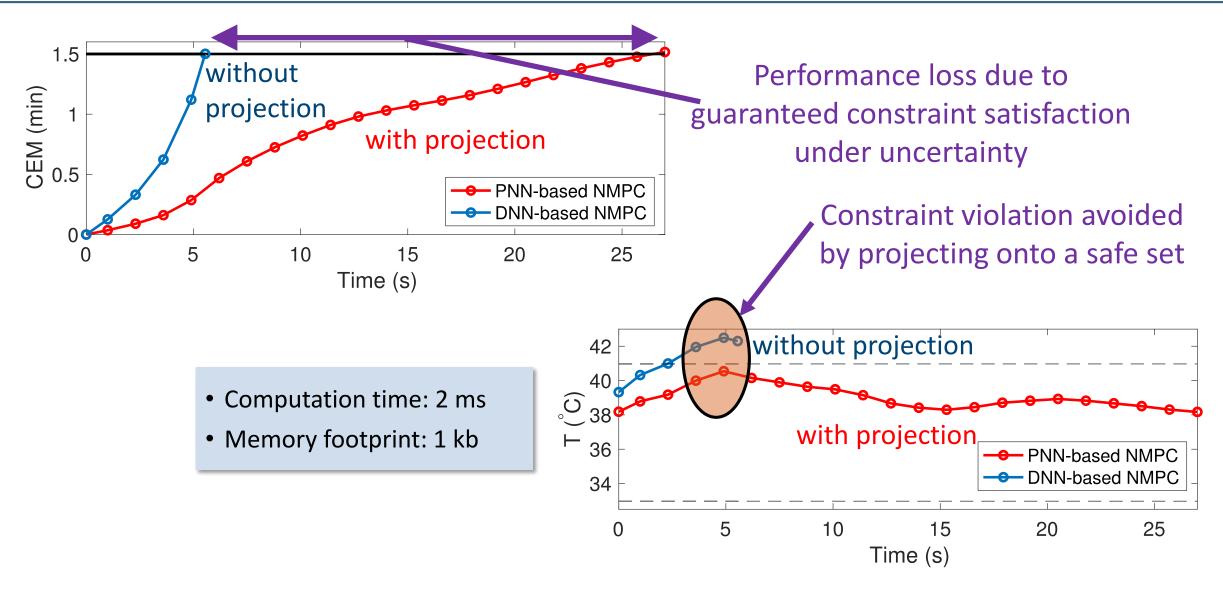
## **Computation Times**

Average computation time reduced by up to a factor of 100



#### **Real-time Control Experiments**

Safety achieved at the expense of performance



## **Takeaways**

- Predictive control is essential for effective LTP treatment of complex surfaces:
  - Controlled environments for studying plasma effects
  - Safe and effective LTP devices for point-of-use applications
  - Automated and robotic control for LTP processing of (bio)materials
- Learning-based methods can create unique opportunities for:
  - Leveraging high-fidelity LTP models along with data-driven approaches to learn and control hard-to-model plasma and surface phenomena
  - Handling uncertainties in real-time decision making towards ensuring safe and repeatable LTP treatments